

U.S.S.N. 09/941,537

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Chen et al.

Group Art Unit: 1756

Serial No.: 09/941,537

Examiner: J. S. Ruggles

Filed: 08/29/2001

In Response to Office Action

Dated: 09/11/2003

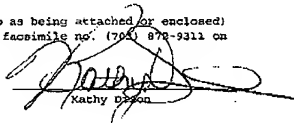
For: METHOD FOR REDUCING LIGHT REFLECTANCE IN A PHOTOLITHOGRAPHIC
DUAL DAMASCENE TRENCH PATTERNING PROCESS

Attorney Docket No.: 67,200-477

Certificate of Facsimile Transmission

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Patent Office via facsimile no. (704) 878-9311 on the date shown below.

Date: Nov. 10/03


Kathy Olson

Request For Reconsideration

Assistant Commissioner
for Patents
P.O. Box 1450
Alexandria, Va 22313-1450

Dear Sir:

In response to an Office Action mailed 09/11/2003,
Applicants respectfully request entry of the following amendments
to either place the claims in condition for allowance or place
the claims in better form for appeal. Please consider the
following remarks.

Do Not
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11/19/03
JSR